



FTW

**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Hiroyoshi TOMINAGA et al.

Group Art Unit: 3723

Application No.: 10/500,278

Examiner: M. RACHUBA

Filed: June 29, 2004

Docket No.: 120214

For: WAFER DOUBLE-SIDE POLISHING APPARATUS AND DOUBLE-SIDE  
POLISHING METHOD

**AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the August 31, 2007 Office Action, please consider the following:

**Amendments to the Claims** as reflected in the listing of claims; and

**Remarks.**